



Docket No.: 53074-026

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor Application of

Tetsuzo Ueda

Serial No.: 09/904,131

Group Art Unit: 1765

Filed: July 11, 2001

Examiner: Matthew Song

For: LAYERED SUBSTRATES FOR EPITAXIAL PROCESSING AND DEVICE

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TC 1700

THE COMMISSIONER FOR PATENTS AND TRADEMARKS  
Washington, DC 20231

Dear Sir:

Transmitted herewith is an Amendment in the above identified application.



No additional fee is required.



Applicant is entitled to small entity status under 37 CFR 1.27



Also attached:

The fee has been calculated as shown below:

	NO. OF CLAIMS	HIGHEST PREVIOUSLY PAID FOR	EXTRA CLAIMS	RATE	FEE
Total Claims	20	23	0	\$18.00 =	\$0.00
Independent Claims	6	7	0	\$84.00 =	\$0.00
Multiple claims newly presented					\$0.00
Fee for extension of time					\$0.00
Total of Above Calculations					\$0.00



Please charge my Deposit Account No. 500417 in the amount of \$0.00. An additional copy of this transmittal sheet is submitted herewith.



The Commissioner is hereby authorized to charge payment of any fees associated with this communication or credit any overpayment, to Deposit Account No. 500417, including any filing fees under 37 CFR 1.16 for presentation of extra claims and any patent application processing fees under 37 CFR 1.17.

Respectfully submitted,

MCDERMOTT, WILL & EMERY

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Docket No.: 53074-02

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Tetsuzo Ueda

Serial No.: 09/904,131

Filed: July 11, 2001

Group Art Unit: 1765

Examiner: Matthew Song

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For: LAYERED SUBSTRATES FOR EPITAXIAL PROCESSING AND DEVICE

SUPPLEMENTAL AMENDMENT

Commissioner for Patents  
Washington, DC 20231

Sir:

In furtherance to the complete amendment filed on March 17, 2003, which was fully responsive to the Office Action dated January 6, 2003, please amend the above-identified application as follows:

IN THE CLAIMS

Please add the following new claims:

--29. An epitaxial growth method comprising:

growing an epitaxial layer on a first side of a substrate at an elevated temperature without rotating the substrate; and

without cooling down to room temperature, growing an epitaxial layer on an opposing side of the substrate without rotating the substrate.

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